

Practitioner's Docket No.: 782_200



PATENT

2834
5-13-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: Tomohiko SHIBATA, Yukinori NAKAMURA and
Mitsuhiro TANAKA

Ser. No.: 09/997,997

Art Unit: 2834

Filed: November 30, 2001

Examiner: Not Assigned

Confirmation No.: 3908

For: A SUBSTRATE USABLE FOR AN ACOUSTIC SURFACE WAVE DEVICE, A METHOD
FOR FABRICATING THE SAME SUBSTRATE AND AN ACOUSTIC SURFACE WAVE
DEVICE HAVING THE SAME SUBSTRATE

I hereby certify that this correspondence is being deposited with
the United States Postal Service as first class mail addressed to
Assistant Commissioner for Patents, Washington D.C. 20231
on February 28, 2002.

Elizabeth A. VanAntwerp
Elizabeth A. VanAntwerp

Assistant Commissioner for Patents
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, the attention of the Patent and Trademark Office is hereby
directed to the reference listed on the attached Form PTO-1449. A copy of the reference listed on
Form PTO-1449 is attached.

Reference AA is discussed at page 1 of the present specification.

The above information is presented so that the Patent and Trademark Office may, in the first
instance, determine any materiality thereof to the claimed invention. It is respectfully requested that
the information be expressly considered during the prosecution of this application, and that the
reference be made of record therein and appear among the "References Cited" on any patent to issue
therefrom.

The Commissioner is hereby authorized to charge any additional fees associated with this
communication or credit any overpayment to Deposit Account No. 50-1446.

Respectfully submitted,

Kevin C. Brown

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February 28, 2002
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US DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 1 of 1

Complete if Known

Application Number	09/997,997
Filing Date	November 30, 2001
First Named Inventor	Tomohiko SHIBATA
Art Unit	2834
Examiner Name	Not Assigned
Confirmation No.	3908
Attorney Docket No.	782_200

U.S. PATENT DOCUMENTS

Exam. Initial	Document Number	Date	Name	Class	Sub Class	Filing Date

FOREIGN PATENT DOCUMENTS

Document Number	Date	Country	Class	Sub Class	Translation	Abstract

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages etc.)

AA	S. Kaneko, et al, "Epitaxial Growth of AlN Film by Low-pressure MOCVD in Gas-Beam-Flow Reactor," Journal of Crystal Growth, 115 (1991), pp. 643-647.

Examiner:	Date Considered:
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.